



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Kazuhiko NAGANO, et al.

Appln. No.: 10/074,258

Group Art Unit: NOT YET ASSIGNED

Confirmation No.: 5060

Examiner: NOT YET ASSIGNED

Filed: February 14, 2002

For: OPTICAL MODELING DEVICE AND EXPOSURE UNIT

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Prior to examination, please amend the above-identified application as follows:

**IN THE SPECIFICATION:**

**Page 2, Please delete the first full paragraph and replace with the following new paragraph:**

A conventional optical modeling device used for such an optical modeling system is divided into a laser plotter type optical modeling device using a laser plotter for scanning and a movable mirror type modeling device using a movable mirror for scanning. Both types of the optical modeling devices can be referred to an issue titled, Maruya, Yoji. 1992. Hikari zokei shisutemu no kiso, genjou, mondaiten. (Foundation, status quo, and issues in optical molding systems technology.) Kata Gijutsu (Die and Mold Technology) 7, no. 10:18-23.